

CVD Equipment (Chemical Vapor Deposition)

Feature

- Order made of LP-CVD, MO-CVD, or Plasma-Enhanced CVD
- Accident Preventing Function due to safety monitor system
- Realize a high purity thin film deposition due to a low leak mechanism
- Available efficient film deposition by automatic operation



CNT-CVD equipment



Silicon nano wire generating equipment



Low & Atmosphere Pressure complexed CVD equipment



GaN thin film MO-CVD equipment